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Docket No.: SON-1908/DIV  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Takeshi Nogami et al.

Application No.: 10/759,194

Confirmation No.: 7751

Filed: January 20, 2004

Art Unit: 2823

For: METHOD FOR PRODUCING  
SEMICONDUCTOR DEVICE, POLISHING  
APPARATUS, AND POLISHING METHOD

Examiner: F. L. Toledo

**AMENDMENT AFTER FINAL ACTION (37 C.F.R. SECTION 1.116)**

MS AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

*Do not enter  
FLT  
4/26/06*

Dear Sir:

**INTRODUCTORY COMMENTS**

In response to the Office Action dated January 9, 2006, please amend the above-identified U.S. patent application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 11 of this paper.